## Supporting Information

Modulating surface morphology and thin film transistor performance of bi-thieno[3,4-c]pyrrole-4,6-dione based polymer semiconductor by altering pre-aggregation in solution

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## Table of Contents

Figure S1 TGA and DSC curves of P1

Table S1 The transistor performance of P1 films deposited under different lifting rates

Figure S2 AFM images of P1 film dip coated at 40 °C and 50 °C

Figure S3 SEM images of P1 film dip coated at 60 °C, 70 °C, 80 °C and 90 °C

Figure S4 Transfer and output curves of **P1** film dip coated at different solution temperatures.

Table S2 The transistor performance of **P1** films deposited by variable-temperature drop casting

Figure S5 Elemental analysis of **P1** 

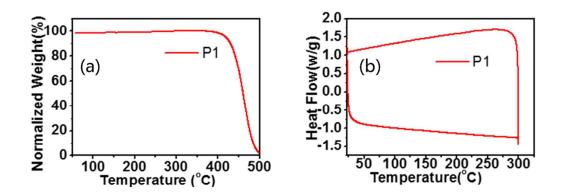


Figure S1. (a) TGA and (b) DSC curves of P1

Lifting rate mm / min	$\mu_{\max(av)}^{a}$ cm <sup>2</sup> / (V·s)	V <sub>th</sub> V	$I_{on}/I_{off}$
1	0.19 (0.12)	-10~-15	10 <sup>5~6</sup>
5	0.28 (0.19)	-10~-20	10 <sup>5~6</sup>
10	0.43 (0.29)	-5~-20	10 <sup>5~6</sup>
25	0.54 (0.35)	-10~-20	10 <sup>5~6</sup>
50	0.41 (0.26)	-3~-15	10 <sup>5~6</sup>
100	0.18 (0.16)	-10~-20	10 <sup>5~6</sup>

Table S1 Transistor performances of P1 films dip-coated at different lifting rates

<sup>a</sup> The solution concentration and temperature are not optimized

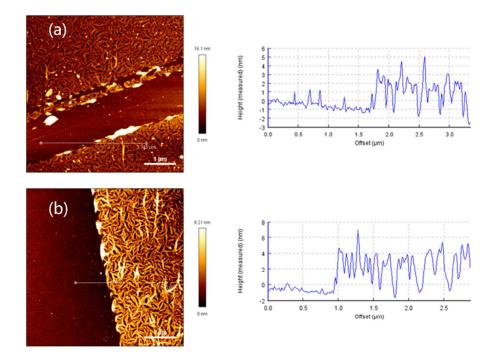


Figure S2. AFM images of P1 dip-coated at temperature of (a) 40  $^{\circ}$ C and (b) 50  $^{\circ}$ C

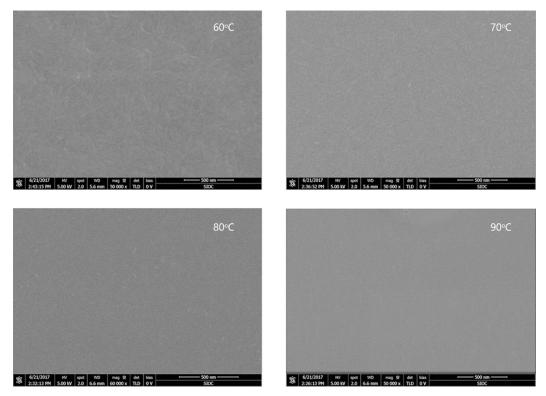


Figure S3. SEM images of P1 dip-coated at temperature of 60 °C, 70 °C, 80 °C and 90 °C

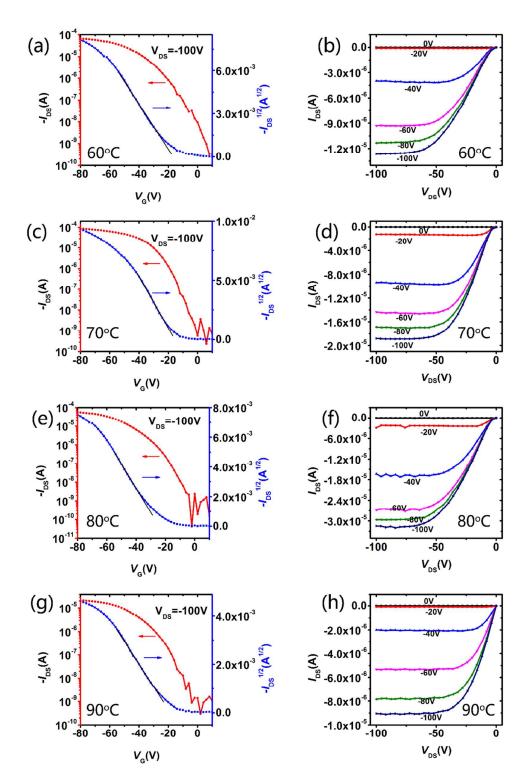


Figure S4. Transfer curves (a, c, e, g) and output curves (b, d, f, h) of P1 films dip-coated at different solution temperatures.

Solution temperature °C	µ <sub>max</sub> /µ <sub>ave</sub> cm² / (V⋅s)	V <sub>th</sub> V	I <sub>on</sub> /I <sub>off</sub>
20	0.027 (1.78±0.57)×10 <sup>-2</sup>	21.87±2.46	10 <sup>5-6</sup>
50	0.085 (4.16±2.45)×10 <sup>-2</sup>	18.97±3.71	10 <sup>5-6</sup>
60	0.199 (5.19±4.78)×10 <sup>-2</sup>	19.31±5.82	10 <sup>5-6</sup>
70	0.131 (1.07±0.25)×10 <sup>-1</sup>	35.33±5.63	10 <sup>5-6</sup>
80	0.185 (1.64±0.22)×10 <sup>-1</sup>	24.33±5.82	10 <sup>5-6</sup>
90	0.148 (7.02±4.16)×10 <sup>-2</sup>	31.73±5.35	10 <sup>5-6</sup>

Table S2. Transistor performance of P1 film fabricated by drop-casting (solution: 0.05 mg / mL TCE)

	(4)大约百分含	·式或结构式 :( <sup>1量 :</sup> C 7 / いい 斗学院上海有	- 1-1 9	NI-6	7	
	TEN			所报告	,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,	
送样单位:高分子材料化学样品名称:WHZ-7-59						
送样者:	吴洪多			登记编号:	2393	
		分		结果		
样品	重量	1.785	mg	2,708	mg	mg
百	N	123	%	1.35	%	%
分 含	C	70-93	%	71.08	%	%
量	FI	9.40	%	9.33	%	%
		CP	1.6.3	1/	f日期:20) 年	= 4月1月日

Figure S5. Elemental analysis data of P1